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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO
10/811,617	03/29/2004	Jack H. Linn	125.013US03	2728
7590 02/15/2006		EXAMINER		
Scott V. Lundberg			SARKAR, ASOK K	
Fogg and Associates, LLC P.O. Box 581339			ART UNIT	PAPER NUMBER
Minneapolis, MN 55458-1339			2891	
			DATE MAILED: 02/15/2000	5

Please find below and/or attached an Office communication concerning this application or proceeding.

Supplemental Notice of Allowability

Application No.	Applicant(s)	
10/811,617	LINN ET AL.	$\mathcal{L}(\mathcal{W})$
Examiner	Art Unit	
Asok K. Sarkar	2891	

ASOKIN	. Carrai				
The MAILING DATE of this communication appears on the cover sheet with the correspondence address All claims being allowable, PROSECUTION ON THE MERITS IS (OR REMAINS) CLOSED in this application. If not included herewith (or previously mailed), a Notice of Allowance (PTOL-85) or other appropriate communication will be mailed in due course. THIS NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RIGHTS. This application is subject to withdrawal from issue at the initiative of the Office or upon petition by the applicant. See 37 CFR 1.313 and MPEP 1308.					
1. X This communication is responsive to <u>amendment filed 12/13/2005</u> .					
2. The allowed claim(s) is/are <u>1 and 4-20</u> .					
International Bureau (PCT Rule 17.2(a)). * Certified copies not received: Applicant has THREE MONTHS FROM THE "MAILING DATE" of this conted below. Failure to timely comply will result in ABANDONMENT of the THIS THREE-MONTH PERIOD IS NOT EXTENDABLE. 4. A SUBSTITUTE OATH OR DECLARATION must be submitted. No INFORMAL PATENT APPLICATION (PTO-152) which gives reason [a) including changes required by the Notice of Draftsperson's Pate [a) hereto or 2) to Paper No./Mail Date (b) including changes required by the attached Examiner's Amend Paper No./Mail Date Identifying indicia such as the application number (see 37 CFR 1.84(c)) she each sheet. Replacement sheet(s) should be labeled as such in the header.	ceived. ceived in Application No have been received in this national stage application from the communication to file a reply complying with the requirements this application. te the attached EXAMINER'S AMENDMENT or NOTICE OF n(s) why the oath or declaration is deficient. mitted. ent Drawing Review (PTO-948) attached ment / Comment or in the Office action of according to 37 CFR 1.121(d). OLOGICAL MATERIAL must be submitted. Note the				
DEPOSIT OF and/or INFORMATION about the deposit of BI attached Examiner's comment regarding REQUIREMENT FOR TH	E DEPOSIT OF BIOLOGICAL MATERIAL.				
Attachment(s)					
1. Notice of References Cited (PTO-892)	5. ☐ Notice of Informal Patent Application (PTO-152)				
2. Notice of Draftperson's Patent Drawing Review (PTO-948)	6. Interview Summary (PTO-413),				
Information Disclosure Statements (PTO-1449 or PTO/SB/08), Paper No./Mail Date	Paper No./Mail Date 7. ⊠ Examiner's Amendment/Comment				
Examiner's Comment Regarding Requirement for Deposit of Biological Material	8. ⊠ Examiner's Statement of Reasons for Allowance9. ☐ Other				

DETAILED ACTION

Terminal Disclaimer

1. The terminal disclaimer filed on December 13, 2005 disclaiming the terminal portion of any patent granted on this application, which would extend beyond the expiration date of US 6,825,532 has been reviewed and is accepted. The terminal disclaimer has been recorded.

EXAMINER'S AMENDMENT

- 2. The Applicant's representative was contacted for amending claim 1, for making it in condition for allowance.
- 3. An examiner's amendment to the record appears below. Should the changes and/or additions be unacceptable to applicant, an amendment may be filed as provided by 37 CFR 1.312. To ensure consideration of such an amendment, it MUST be submitted no later than the payment of the issue fee.

Authorization for this examiner's amendment was given in a telephone interview with Scott V. Lundberg on January 6, 2006.

The application has been amended as follows:

In claim 1, line 4, following the word "material", insert -- under conditions effective to coalesce a substantially planar zone formed by the implantation of ions through the first surface of the semiconductor material to form a gettering zone and further -- .

In claim 1, line 5, following the word "material", delete "and bonding a handle wafer to the first surface of the semiconductor material." and insert - - forming an

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insulating bond layer on a surface of a handle wafer; and bonding the insulating bond layer to the first surface of the semiconductor material. - - .

Claims 2 and 3 were cancelled.

Allowable Subject Matter

- 4. Claims 1 and 4 20 are now allowed.
- 5. The following is an examiner's statement of reasons for allowance:

Claims 1 and 4 – 8 recite, inter alia, a method of forming a semiconductor device comprising the steps of implanting ions through a first surface of a monocrystalline semiconductor material to a selected depth forming an amorphous layer adjacent the first surface, heating the semiconductor material under conditions effective to coalesce a substantially planer zone formed by the implantation of ions through the first surface of the semiconductor material to form a gettering zone and further to convert the amorphous layer to a first layer of semiconductor material, forming an insulating bond layer on a surface of the handle wafer and bonding the insulating bond layer to the first surface of the semiconductor material. The art of record does not disclose or anticipate the above limitation in combination with other claim elements nor would it be obvious to modify the art of record so as to form a device including the above limitation.

Claims 9 – 20 recite, inter alia, a method of forming a semiconductor device comprising the steps of implanting ions through a first surface of the wafer to form an amorphous layer adjacent the first surface, annealing the wafer to convert the amorphous layer to a first monocrystalline semiconductor layer, bonding a handle wafer to the first surface of the wafer and forming semiconductor devices on the second

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surface of the wafer. The art of record does not disclose or anticipate the above limitation in combination with other claim elements nor would it be obvious to modify the art of record so as to form a device including the above limitation.

Conclusion

- 6. Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."
- 7. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Asok K. Sarkar whose telephone number is 571 272 1970. The examiner can normally be reached on Monday Friday (8 AM- 5 PM).

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, William B. Baumeister can be reached on 571 272 1722. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

8. Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR.

Status information for unpublished applications is available through Private PAIR only.

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Asok K. Sarkar

February 13, 2006

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Primary Examiner

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